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CONFIRMATION NO. 3769

<b>SERIAL NUMBER</b> 10/756,830	<b>FILING OR 371(c) DATE</b> 01/14/2004 <b>RULE</b>	<b>CLASS</b> 438	<b>GROUP ART UNIT</b> 2891	<b>ATTORNEY DOCKET NO.</b> 55071-329
<b>APPLICANTS</b> Douglas Van Den Broeke, Sunnyvale, CA; Jang Fung Chen, Cupertino, CA; Thomas Laidig, Point Richmond, CA; Kurt E. Wampler, Sunnyvale, CA; Stephen Duan-Fu Hsu, Freemont, CA;				
<b>** CONTINUING DATA *****</b> This appln claims benefit of 60/439,807 01/14/2003 <i>done</i>				
<b>** FOREIGN APPLICATIONS *****</b> <i>NONE done</i>				
<b>IF REQUIRED, FOREIGN FILING LICENSE GRANTED</b> <b>** 04/15/2004</b>				
Foreign Priority claimed <input type="checkbox"/> yes <input checked="" type="checkbox"/> no 35 USC 119 (a-d) conditions <input type="checkbox"/> yes <input checked="" type="checkbox"/> no <input type="checkbox"/> Met after met Verified and Acknowledged <i>Chenmark</i> Examiner's Signature <i>CME</i> Initials		<b>STATE OR COUNTRY</b> CA	<b>SHEETS DRAWING</b> 15	<b>TOTAL CLAIMS</b> 21
				<b>INDEPENDENT CLAIMS</b> 3
<b>ADDRESS</b> 20277				
<b>TITLE</b> Method and apparatus for providing optical proximity features to a reticle pattern for deep sub-wavelength optical lithography				
<b>FILING FEE RECEIVED</b> 1168	FEES: Authority has been given in Paper No. _____ to charge/credit DEPOSIT ACCOUNT No. _____ for following:		<input type="checkbox"/> All Fees <input type="checkbox"/> 1.16 Fees ( Filing ) <input type="checkbox"/> 1.17 Fees ( Processing Ext. of time ) <input type="checkbox"/> 1.18 Fees ( Issue ) <input type="checkbox"/> Other _____ <input type="checkbox"/> Credit	